



Substitute Form PTO-1449 (Modified) Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 14414-011001	Application No. 10/633,955
	Applicant Louis J. Bintz et al.		
	Filing Date August 4, 2003	Group Art Unit 1732	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
MDV	AA	5,120,339	06/09/92	Markovich et al.			
↑	AB	5,133,037	07/21/92	Yoon et al.		↑	
	AC	5,198,513	03/30/93	Clement et al.			
	AD	5,219,788	06/15/93	Abernathey et al.			
	AE	5,223,356	06/29/93	Kumar et al.			
	AF	5,370,969	12/06/94	Vidusek			
	AG	5,433,895	07/18/95	Jeng et al.			
	AH	5,480,687	01/02/96	Heming et al.			
	AI	5,635,576	06/03/97	Foll et al.			
	AJ	5,714,304	02/03/98	Gibbons et al.			
	AK	5,776,374	07/07/98	Newsham et al.			
	AL	5,783,319	07/21/98	Reisfeld et al.			
	AM	5,811,507	09/22/98	Chan et al.			
	AN	5,861,976	01/19/99	Hoekstra			
	AO	6,002,828	12/14/99	Hult et al.			
	AP	6,019,906	02/01/00	Jang et al.			
	AQ	6,031,945	02/29/00	You et al.			
	AR	6,126,867	10/03/00	Kanitz et al.			
	AS	6,294,573	09/25/01	Curtin et al.			
	AT	6,303,730	10/16/01	Fries et al.			
	AU	6,306,563	10/23/01	Xu et al.			
	AV	6,323,361	11/27/01	Wu et al.			
	AW	6,335,149	01/01/02	Xu et al.			
	AX	6,419,989	07/16/02	Betz et al.			
MDV	AY	10/264,461	N/A	Dinu et al.			

Foreign Patent Documents or Published Foreign Patent Applications							
Examiner	Desig.	Document	Publication	Country or	Class	Subclass	Translation
Examiner Signature <i>M. Vuyat</i>				Date Considered <i>6/27/05</i>			
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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							Yes	No
	AZ							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
MDV	AAA	Bailey et al., "Step and flash imprint lithography: Template surface treatment and defect analysis," <u>J. Vac. Sci. Technol. B</u> , 2000, 18(6):3572-3577
↑	ABB	Chen et al., "Thermosetting Polyurethanes with Stable and Large Second-Order Optical Nonlinearity," <u>Macromolecules</u> , 1992, 25:4032-4035
	ACC	Grote et al., "Effect of conductivity and dielectric constant on the modulation voltage for optoelectronic devices based on nonlinear optical polymers," <u>Opt. Eng.</u> , 2001, 40(11):2464-2473
	ADD	Ma et al., "A Novel Class of High-Performance Perfluorocyclobutane-Containing Polymers for Second-Order Nonlinear Optics," <u>Chem. Mater.</u> , 2000, 12:1187-1189
	AEE	Ma et al., "Highly Efficient and Thermally Stable Nonlinear Optical Dendrimer for Electrooptics," <u>J. Am. Chem. Soc.</u> , 2001, 123:986-987
	AFF	Mao et al., "Progress toward Device-Quality Second-Order Nonlinear Optical Materials. 1. Influence of Composition and Processing Conditions on Nonlinearity, Temporal Stability, and Optical Loss," <u>Chem. Mater.</u> , 1998, 10:146-155
↓	AGG	Oh et al., "Electro-optic polymer modulators for 1.55 μm wavelength using phenyltetraene bridged chromophore in polycarbonate," <u>Appl. Phys. Lett.</u> , 2000, 76(24):3525-3527
MDV	AHH	Resnick et al., "Release Layers for Contact and Imprint Lithography," <u>Semicon. Int.</u> , June 2002, online version, 7 pgs.

Examiner Signature <i>M. Vargat</i>	Date Considered <i>6/27/08</i>
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